

ABSTRACT OF THE DISCLOSURE

An apparatus for fabricating a plasma display panel, the apparatus forming a protection film on a substrate of a plasma display panel in a display
5 area, includes (a) a vacuum chamber, (b) a feeder which feeds the substrate in a first direction in the vacuum chamber, and (c) a plurality of evaporation sources located in alignment with the display area of the substrate when the substrate is in a film-forming position, wherein at least one of the evaporation sources is located in each of first areas defined as areas extending from edges of a
10 maximum substrate among substrates being able to be fed by the feeder which edges extend in the first direction, inwardly of the substrate by a predetermined length in a second direction perpendicular to the first direction.